

Supporting Information for

High Yield Transfer of Clean Large-Area Epitaxial Oxide Thin Films

Bowen Zhang¹, Chao Yun¹, Judith L MacManus-Driscoll^{1, *}

¹Department of Materials Science and Metallurgy, University of Cambridge, 27 Charles Babbage Road, Cambridge CB3 0FS, United Kingdom

*Corresponding author. E-mail: jld35@cam.ac.uk (Judith L MacManus-Driscoll)

Supplementary Figures

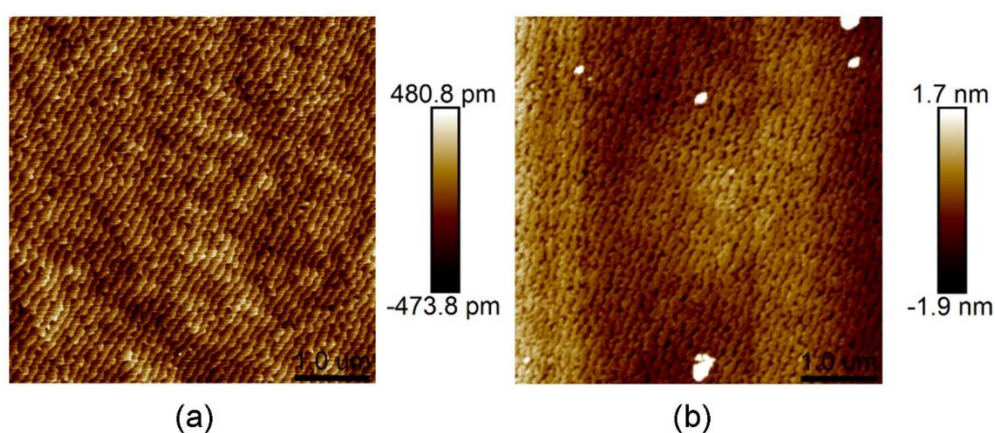


Fig. S1 AFM image of the surface morphology, showing the step-and-terrace structure of SrTiO₃ substrate (a) and 10 nm thick Sr₃Al₂O₆ film on the substrate (b)

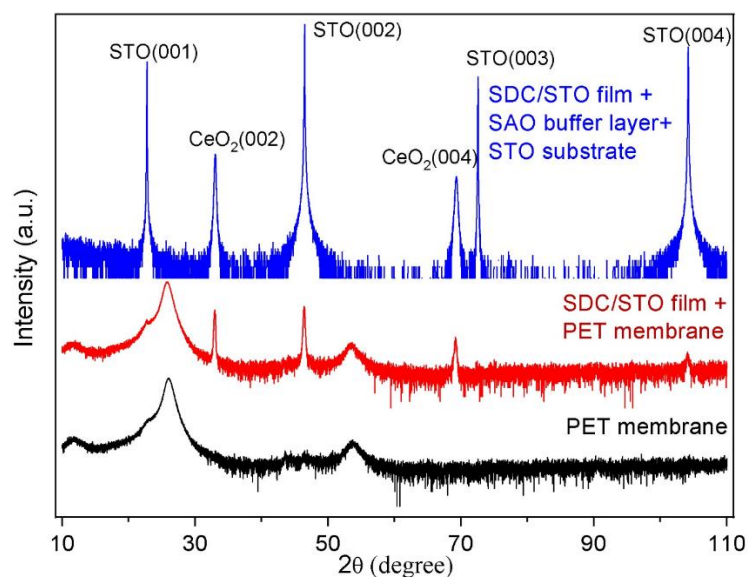


Fig. S2 XRD $2\theta - \omega$ pattern (log scale) of the CeO₂/STO VAN nanocomposite film before and after transfer. The remaining STO peaks after transfer proves the existence of STO matrix phase

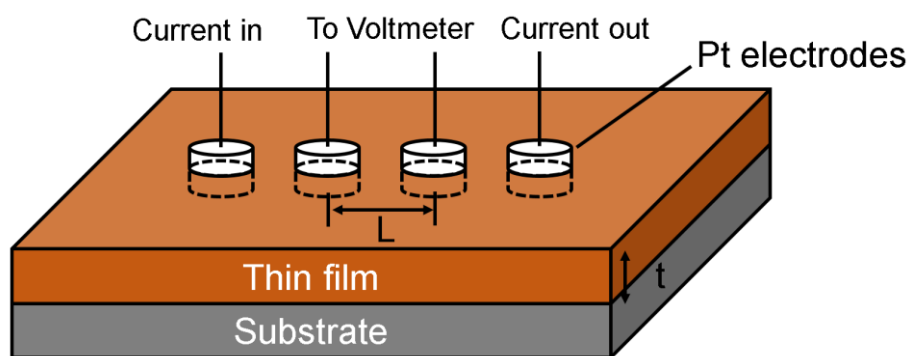


Fig. S3 Illustration of four-probe resistance measurements for measuring the resistivity of the SrRuO₃ film